Experiment No : 5

**Experiment Name**: Observation and Verification of nMOS characteristics.

## Objectives:

- ✓ To find the MOS model parameters for the transistors and then by "pencil & paper" manually calculate the DC characteristics of  $I_{DS}$  current vs  $V_{DS}$  voltage, using simple current equations for MOS model Level 1 to determine a number of corresponding value pairs of  $(I_{DS}; V_{DS})$  with gate-source voltage,  $V_{GS} = a$  constant  $> V_{th}$ .
- ✓ Use circuit simulator of Micro-wind to do a DC simulation of the I<sub>DS</sub> current vs V<sub>DS</sub> voltage and the result of the two methods compared.
- Calculation of the threshold voltage.

## Tools:

Microwind software.

## Theory:

The nMOS transistor I<sub>DS</sub> current versus V<sub>DS</sub> voltage equations are as follows:

- a) **Cut-off mode**:  $I_{DS} = 0$  when  $V_{GS} < 0$ .
- b) Triod/Linear region: IDS =  $k_n \{ (V_{GS} V_{Th}) V_{DS} \frac{1}{2} V_{DS}^2 \}$  when  $V_{DS} < V_{GS} V_{th}$  ----(1)

  In Level 1 SPICE model, IDS =  $\mu_{0.} \frac{\epsilon_0 \epsilon_{SiO_2}}{T_{CS}} \cdot \frac{W}{L} \{ (V_{GS} V_{Th}) V_{DS} \frac{1}{2} V_{DS}^2 \}$
- c) Saturation egion:  $I_{DS} = \frac{1}{2} k_n \{ (V_{GS} V_{Th})^2 (1 + \lambda V_{DS}) \}$  when  $V_{DS} > V_{GS} V_{th}$  ------(2) In level 1 SPICE model  $I_{DS} = \mu_0 \cdot \frac{\epsilon_0 \epsilon_{SiO_2}}{T_{OS}} \cdot \frac{W}{L} (V_{GS} V_{Th})^2$

when channel modulation effect is neglected the drain current equation (2) can be simplified as

$$I_{DS} = \frac{1}{2} k_n \{ (V_{GS} - V_{Th})^2 \}$$
 when  $V_{DS} > V_{GS} - V_{th}$  -----(3)

The current gain factor  $k_n$  is a constant with unit . This is dependent on MOS transistor geometry (channel length L and channel width W), fabrication process parameters (electron mobility,  $\mu_n$  and gate-oxide capacitance  $C_{\rm OX}$ ).

The factor  $k_n$  can be calculated as  $k_n = k'_n \frac{W}{L}$  where the process conductance parameter

 $k'_n = \mu_n C_{ox} \left[ \frac{A}{V^2} \right]$ . The parameters  $C_{ox}$  stands for gate oxide capacitance per unit area dependent on

gate oxide thickness  $t_{\text{OX}}$ . This can be expressed as  $C_{\text{OX}} = \frac{\epsilon_{ox}}{t_{ox}}$  where the  $\epsilon_{ox} = 3.97$  is the silicone

dioxide permitivity which can be calculated with the knowledge of relative dielectric constant value of silicon dioxide  $\epsilon_{SiO_2}$  and dielectric constant of vacuuam  $\epsilon_0$ . So  $\epsilon_{ox} = \epsilon_{SiO_2} * \epsilon_0$ . The additional parameter of the  $I_{DS}$  and  $V_{DS}$  is the threshold voltage  $V_T$ . The threshold voltage with zero source-substrate

(bulk) voltage can be expressed as  $V_{T0}$ . When the source-substrate (bulk) voltage  $V_{SB}$  is not equal to zero then we call it for nMOS transistor is  $V_{tn}$  and for pMOS is  $V_{tp}$  can be expressed as follows:

$$V_{T_{o}} = V_{T_{oo}} + \gamma (\sqrt{2 \phi_{b} + |V_{SB}|} - \sqrt{2 \phi_{b}})$$

$$V_{T_{o}} = V_{T_{oo}} + \gamma (\sqrt{2 \phi_{b} + (V_{DD} + |V_{BS}|}) - \sqrt{2 \phi_{b}})$$

The table below shows the SPICE MOSFET parameters in level 1

Microwind SPICE symbol	Meaning	Theoritical Symbol	Unit	
VTO	Threshold Voltage	$ m V_{T0}$	V	
TOX	Oxide thickness	$t_{ox}$	nm	
UO	Low-field obility	$\mu_0$		
			V.sec	
PHI	Surface potential	2 φ	V	
GAMMA	Body-bias coefficient	γ	$V^2$	

## Procedure:

(a) Level 1 MOS model equations to calculate DC values for the drain current  $I_{DS}$  vs drain-source voltage  $V_{DS}$ .

- First calculate with a gate-source voltage  $V_{GS}$  = +2.0 V, for each drain-source voltage  $V_{DS}$ ; 0.5, 1.0, 1.5, 2.0, 2.5 the difference  $V_{DS}$  ( $V_{GS}$  ( $V_{GS}$  ( $V_{th}$ ) to determine in which region transistor work. Mark in table 2 equation umber 1 or 2 that should be chosen to calculate the drain current  $I_{DS}$  for the corresponding point ( $I_{DS}$ ,  $V_{DS}$ ). If we consider the 0.25um CMOS processing technology then  $V_{th}$  = 0.45V,  $\mu_0 = \mu_n = 0.06$ ,  $\gamma = 0.4$ ,  $t_{ox} = 0.5$  nm
- Calculate for the voltages  $V_{DS}$ : 0.5, 1.0, 1.5, 2.0, 2.5 volts the drain-current  $I_{DS}$  for each point  $(I_{DS}; V_{DS})$  after having determined a region the transistor works in (linear or saturated) Fill in corresponding value pairs  $(I_{DS}; V_{DS})$  in table 2 for given drain-source DC voltages.

$V_{ m DS}$	0.5	1.0	1.5	2.0	2.5
	-1.05	-0.55	-0.05	0.45	0.95
$V_{DS-}(V_{GS}-V_{tn})$	eqn-1	eqn-1	eqn-1	eqn-2	eqn-2
Manual Calculation I <sub>DS</sub> (uA)	547.56	884.52	1010.88	1011.933	1011.93

Now plot the characteristics curve using excel based data-values of table 1 the curve is like as shown in figure

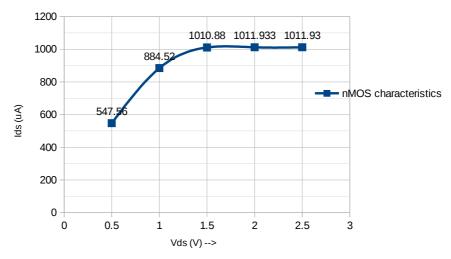


Fig 1: Characteristics of nMOS transistor

- **(b)** Use of "Simulate>MOS characteristics" to generate the DC characteristic  $I_{DSn}$  vs  $V_{DSn}$  for the nMOS transistor in microwind.
  - Open the microwind window and check that the selected foundary is 0.25 um CMOS process from file→ select foundary and choose cmos025.rul. Use Level 1 MOS transistor model.
  - Now generate the nMOS transistor of width and length ratio is  $4\lambda x 2\lambda$  from palate. Then simulate the generated nMOS to check its characteristics curve and compare the curve with the manually generated curve.

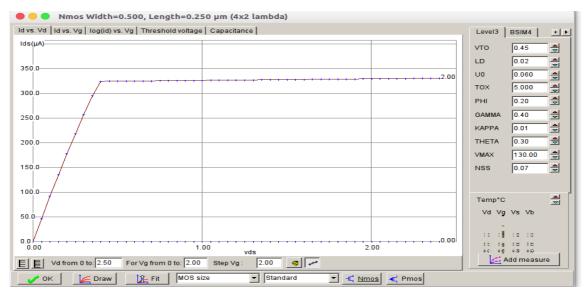


Fig 2: Microwind generated nMOS characteristics curve

**Conclusion:** The characteristics curve of nMOS from manually calculated values of I<sub>DS</sub> doesn't vary significantly from automatically generated characteristics curve using Micro-wind. Micro-wind being a simulation software can include several influencing factor while plotting the characteristics curve.